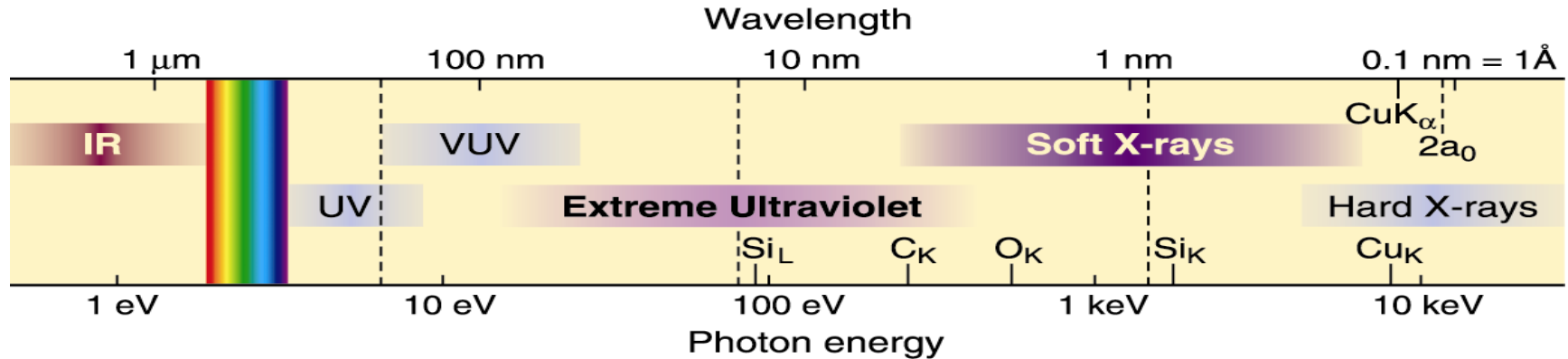


# **Interferometry, spectroscopy and lensless imaging with extreme ultraviolet radiation**

**Stefan Witte**

**Advanced Research Center for Nanolithography  
VU University Amsterdam**

# Extreme ultraviolet radiation

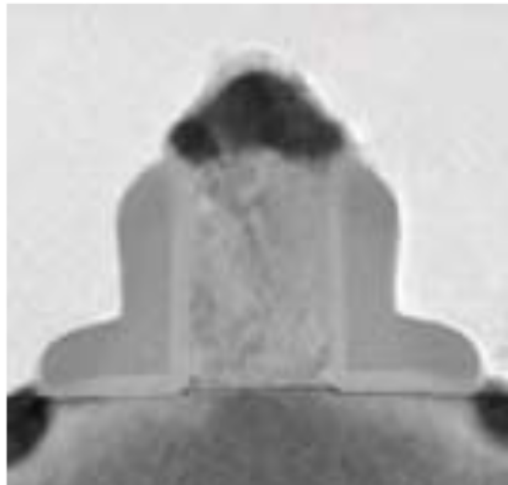


## Outline of this talk:

- Extreme ultraviolet radiation and its applications
- High harmonic generation, lasers and EUV spectroscopy
- EUV interferometry and Fourier transform spectroscopy
- Lensless imaging with EUV radiation
- Conclusions

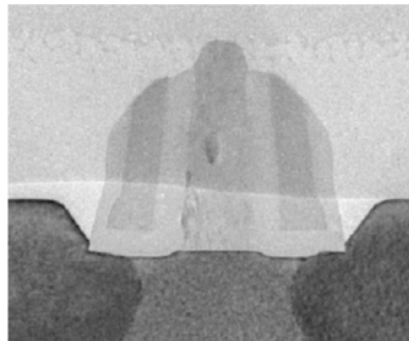
# Typical size of lithographic structures

## (nano)transistors by Intel



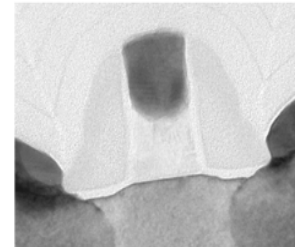
130 nm

2003



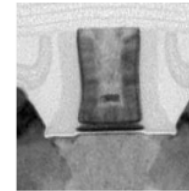
90 nm

2005



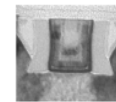
65 nm

2007

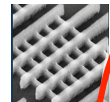


45 nm

2009 – 2011



32 nm



22 nm



??

later

# The inside of a chip

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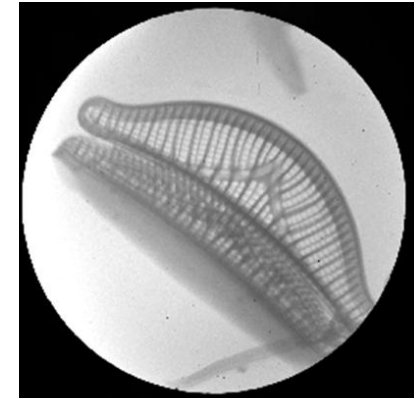


So how do you image this?



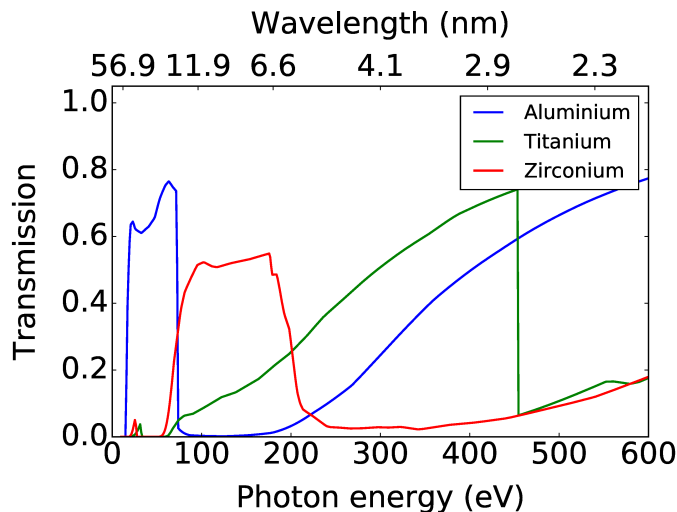
# Interesting properties of EUV radiation

1) Short wavelength  $\rightarrow$  diffraction from nanoscale objects

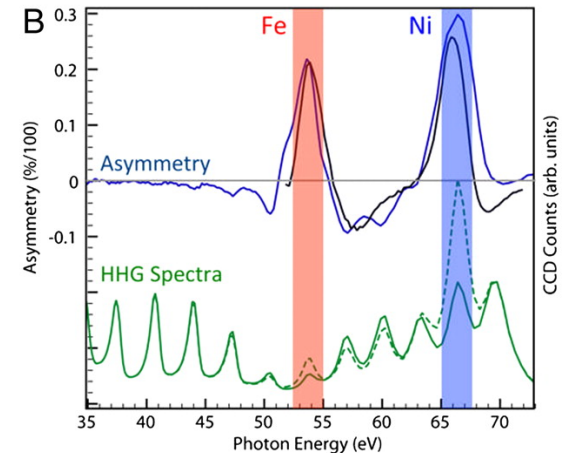
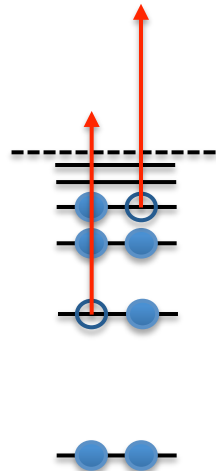


H. Stiel et al., MBI Berlin

2) Element-selectivity  $\rightarrow$  many elements have spectral transmission windows



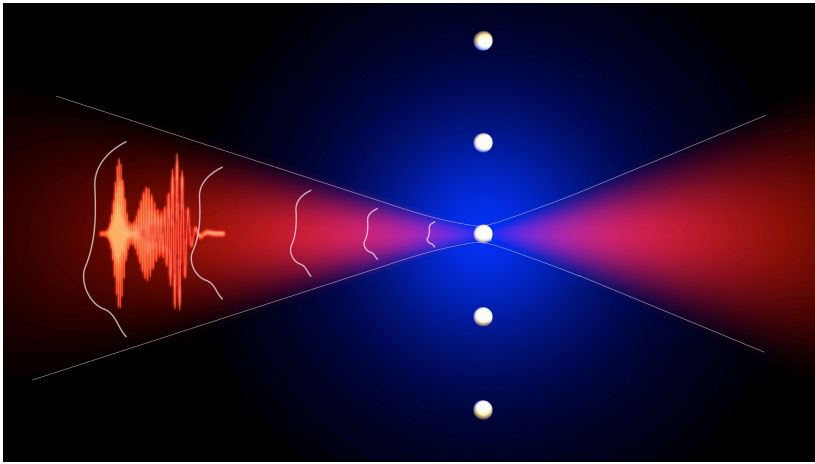
3) High photon energy  $\rightarrow$  provides access to core levels



S. Mathias et al. PNAS **109**, 4792 (2012)

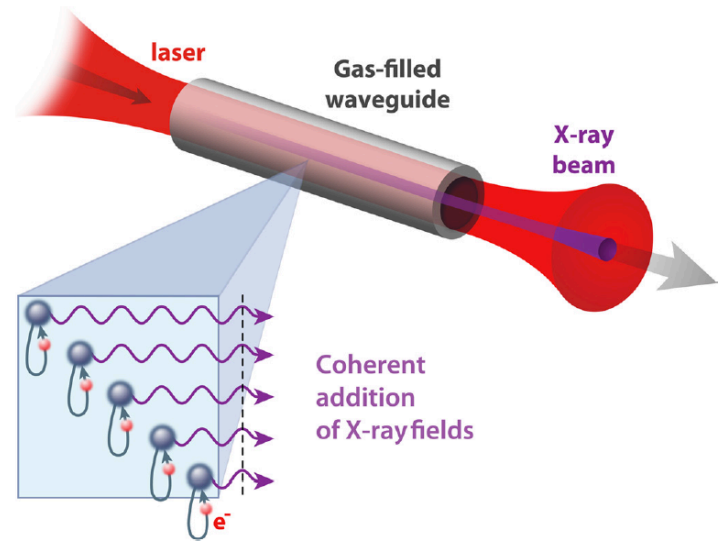
# Table-top EUV sources

## Plasma sources (pumped by laser or electric discharge)



- Incoherent,  $4\pi$  emission
- Nanosecond pulses (typical)
- Several % conversion efficiency
- Multiple Watts average power
- Debris from plasma

## High-harmonic generation



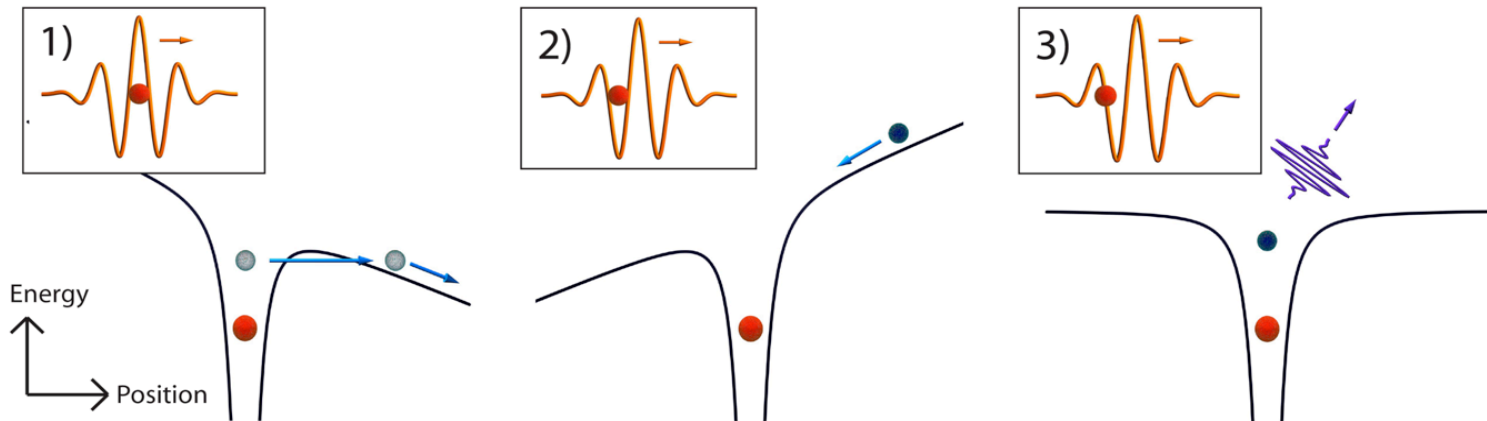
- Coherent, diffraction-limited beams
- Attosecond pulse trains
- Conversion efficiency  $10^{-5} - 10^{-9}$
- $\mu\text{W}$  average power
- Need to separate EUV from IR

# High harmonic generation

Intense laser modifies Coulomb potential  $\rightarrow$  electron tunnels and accelerates in laser field

Field changes sign  $\rightarrow$  electron returns to the parent ion

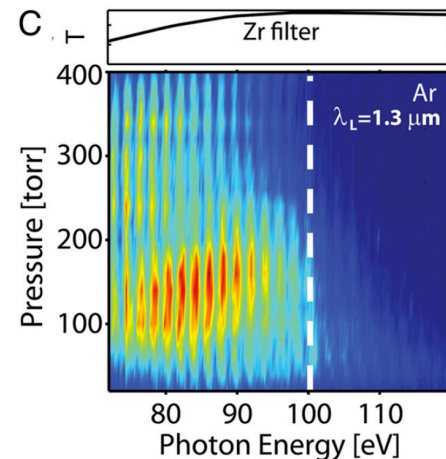
Recollision, electron energy converted into XUV photon



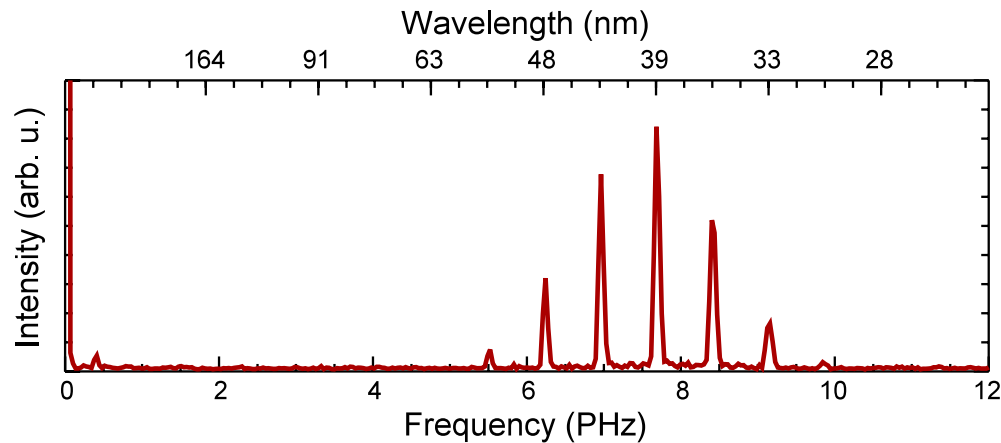
IR and EUV waves need to remain in phase for coherent buildup:

$$\Delta k \approx \underbrace{q \frac{u_{11}^2 \lambda_L}{4 \pi a^2}}_{\text{geometric}} - \underbrace{qp(1 - \eta) \frac{2\pi}{\lambda_L} (\Delta\delta + n_2)}_{\text{atoms}} + \underbrace{qp\eta N_a r_e \lambda_L}_{\text{free electrons}}$$

Need to avoid excessive ionization, limits flux scaling by intensity



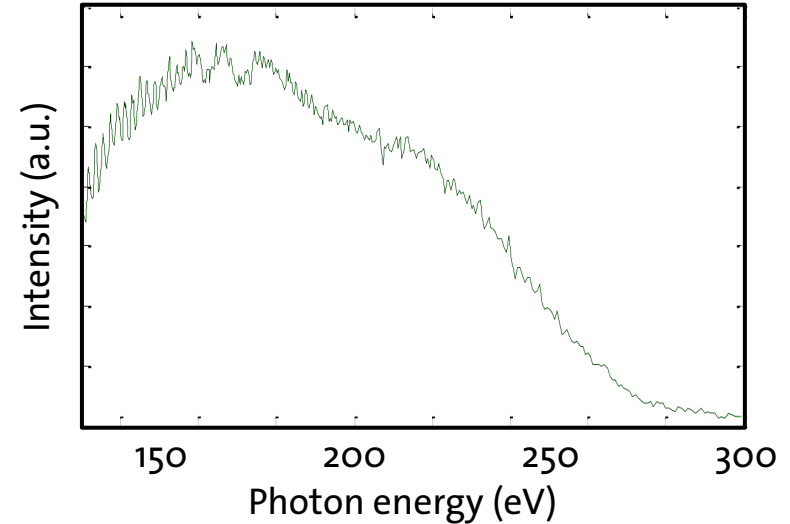
# Typical HHG spectra



HHG in Argon,

$\lambda_{\text{laser}}=800 \text{ nm}$ ,  $E=1 \text{ mJ}$ ,  $30 \text{ fs}$

- Series of discrete odd ‘harmonics’
- Interference of a train of attosecond EUV bursts, produced every half-cycle



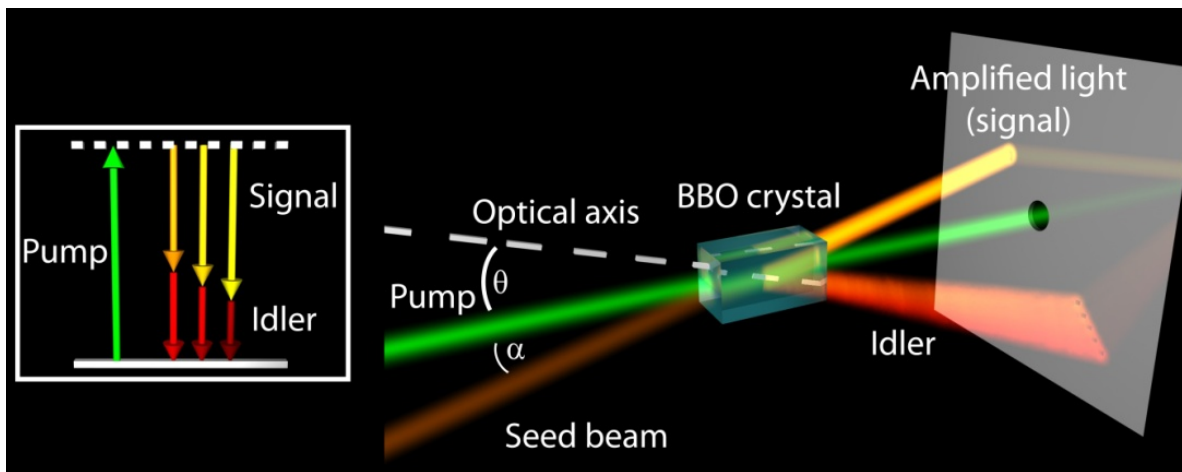
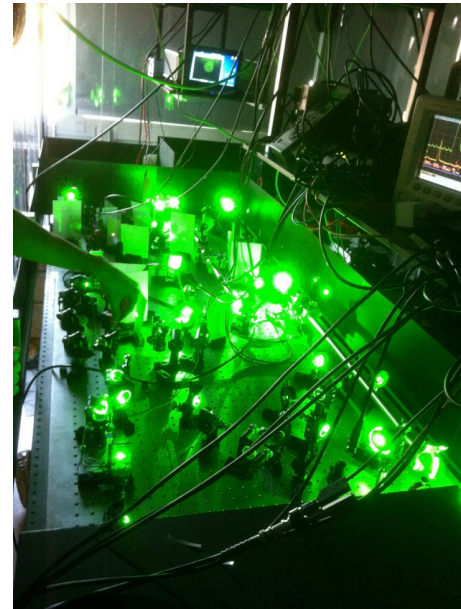
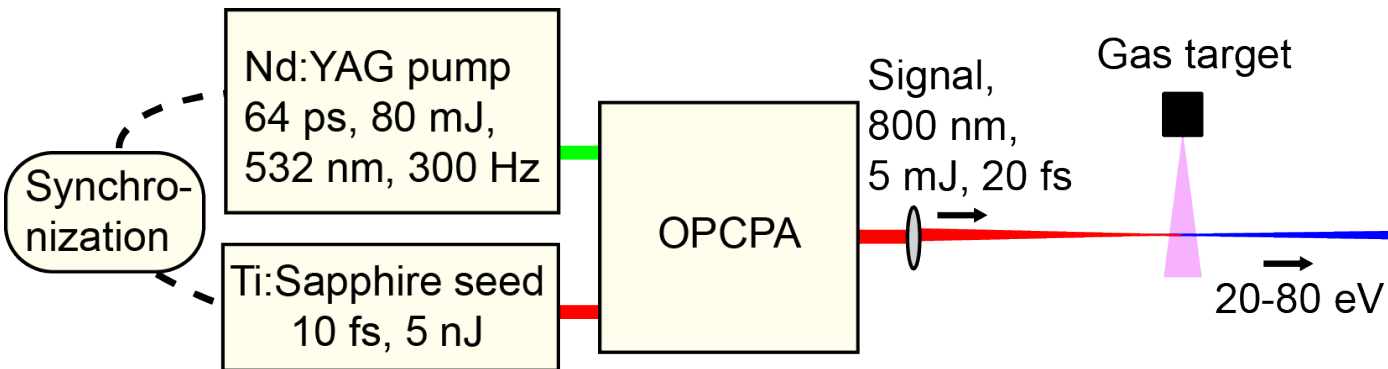
HHG in Helium,

$\lambda_{\text{laser}}=1300 \text{ nm}$ ,  $E=1 \text{ mJ}$ ,  $40 \text{ fs}$

- Harmonics blend into a continuum
- Only few (or one) attosecond bursts

# Coherent EUV source development

- Intense few-cycle laser pulses are needed for HHG.
- Produced by optical parametric chirped pulse amplification (OPCPA).



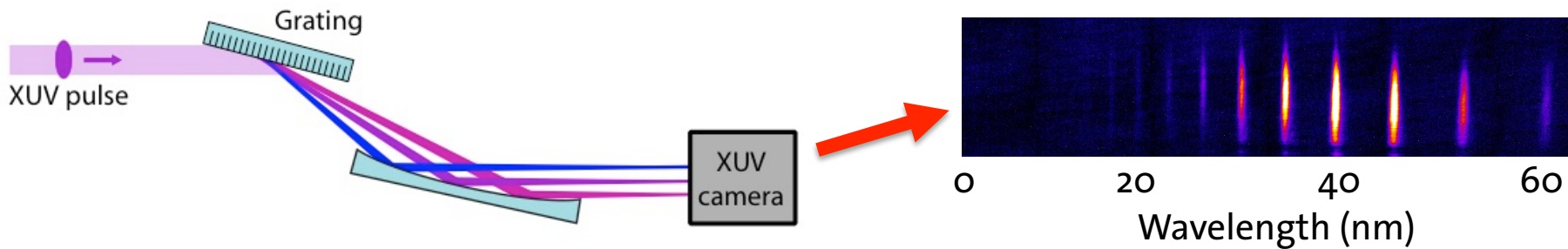
Witte and Eikema, IEEE Sel. Top. Quant. Electron. **18**, 296 (2012)

Witte et al., Opt. Express **14**, 8168 (2006)

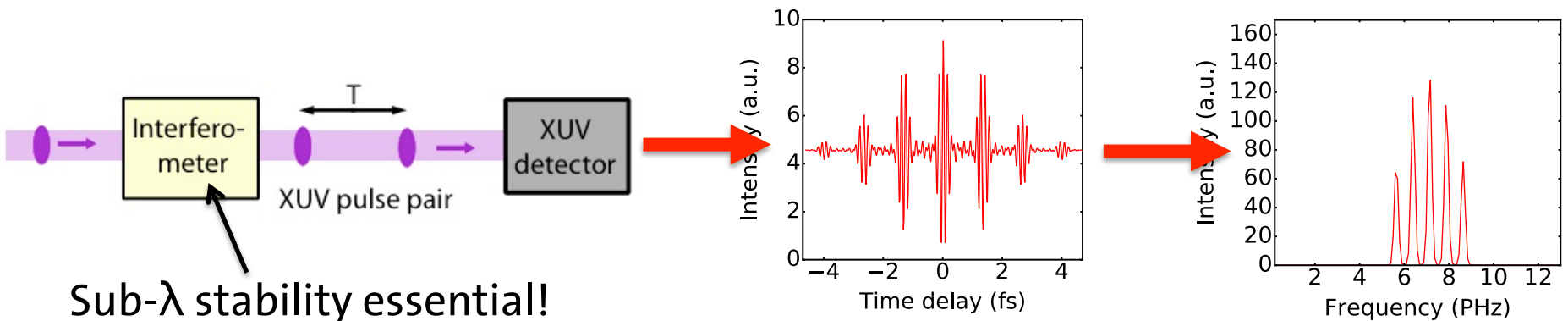


# XUV spectroscopy

**Classical grating-based spectrometer:** use diffraction to disperse different wavelengths over a spatial axis.

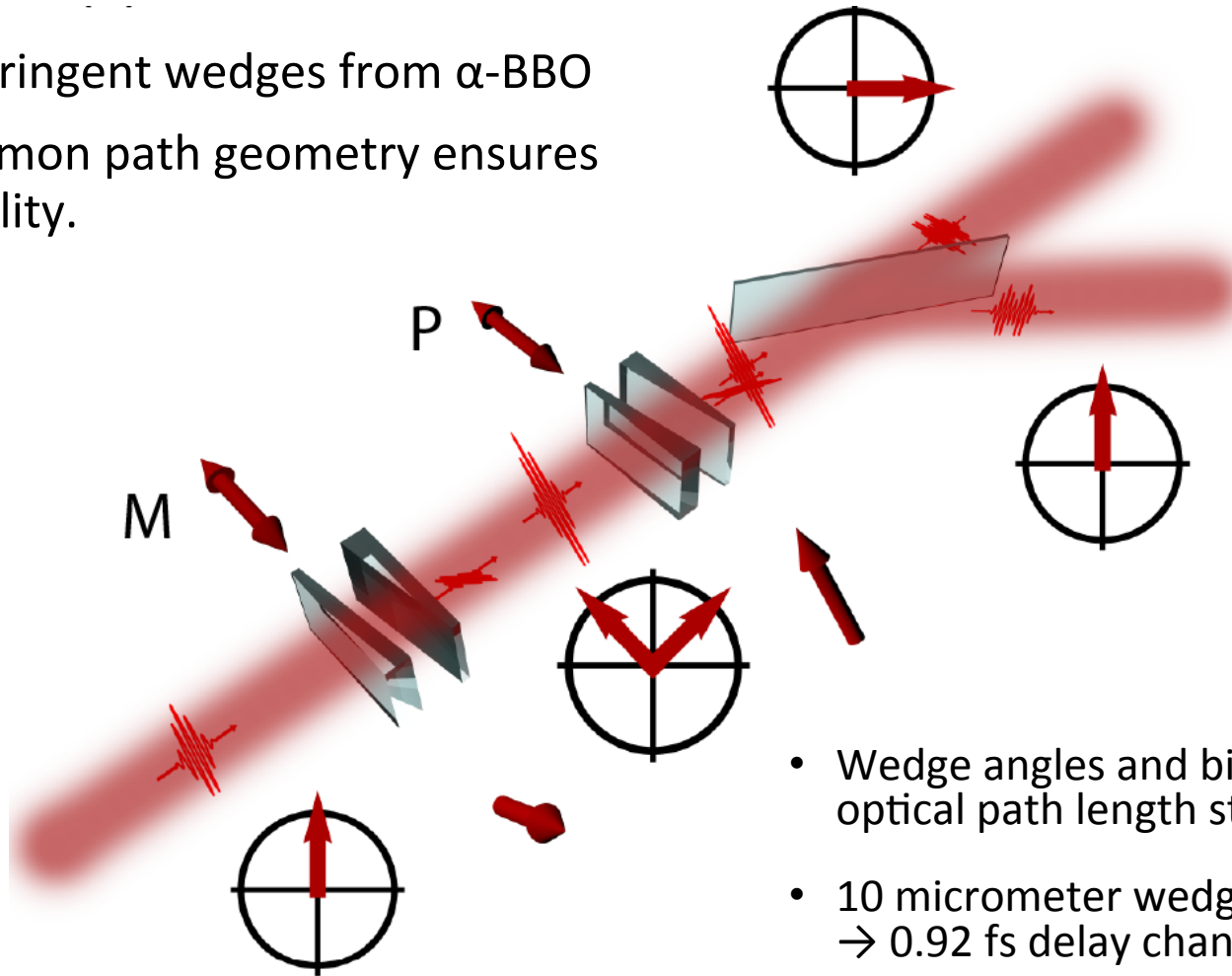


**Fourier-transform spectroscopy:** measure temporal coherence function and retrieve frequency information by Fourier transform.



# Ultra-stable tunable interferometer

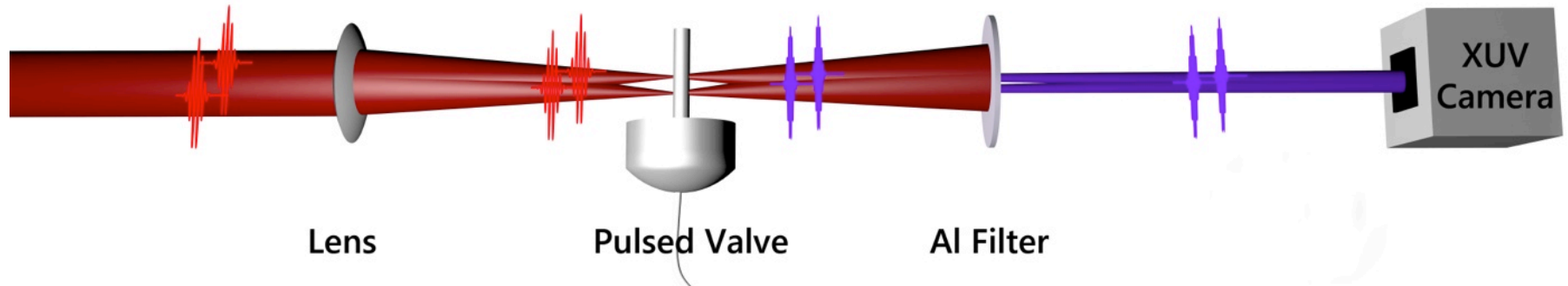
- Birefringent wedges from  $\alpha$ -BBO
- Common path geometry ensures stability.



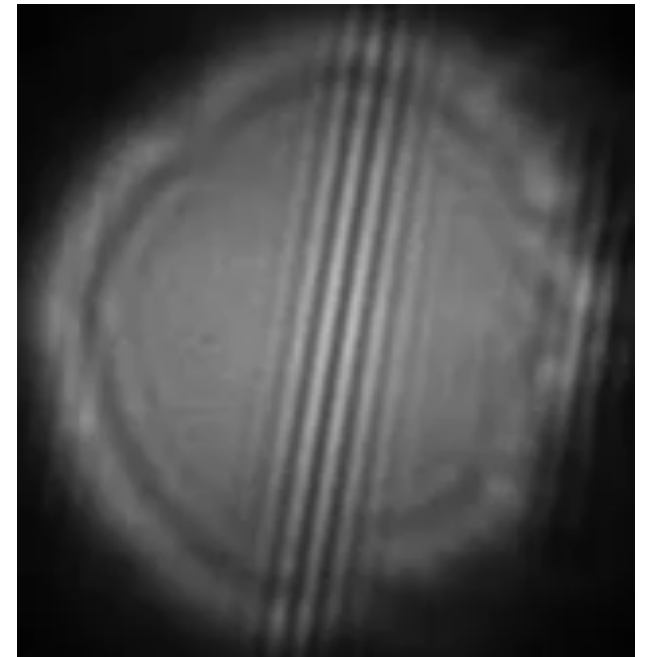
- Wedge angles and birefringence control optical path length step size.
- 10 micrometer wedge displacement  $\rightarrow$  0.92 fs delay change
- Piezo-stage with 5 nanometer precision  $\rightarrow$  0.46 attosecond delay steps possible

# EUV interferometry

- HHG setup combined with ultra-stable common-path interferometer:



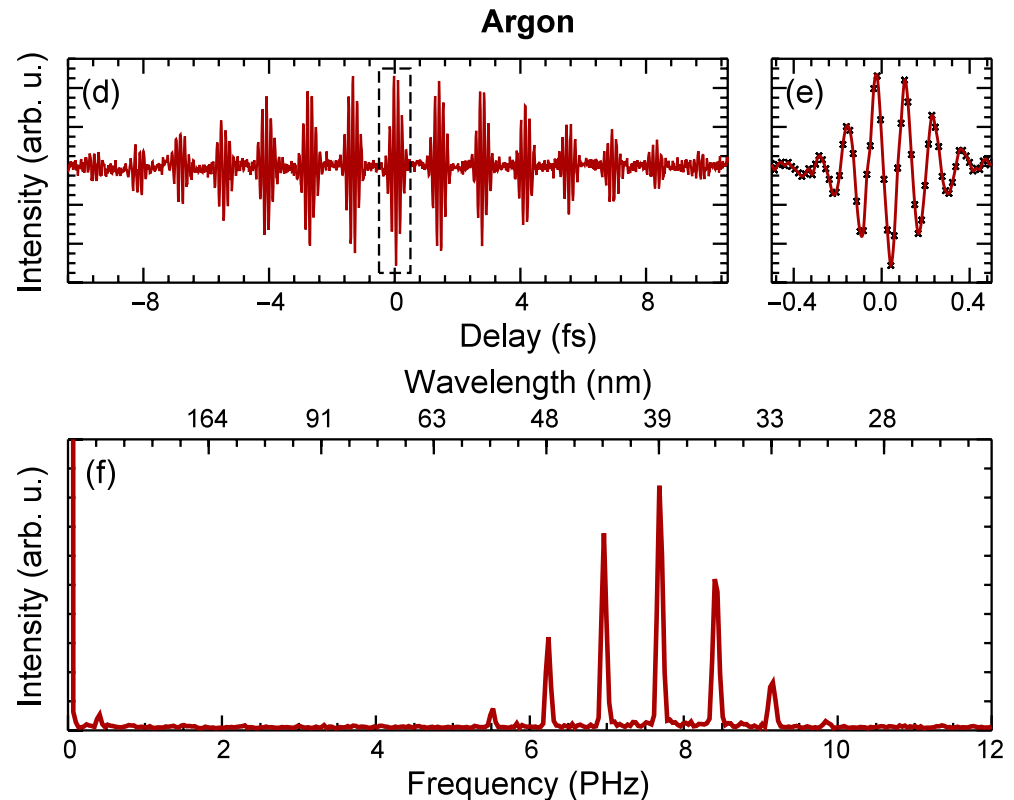
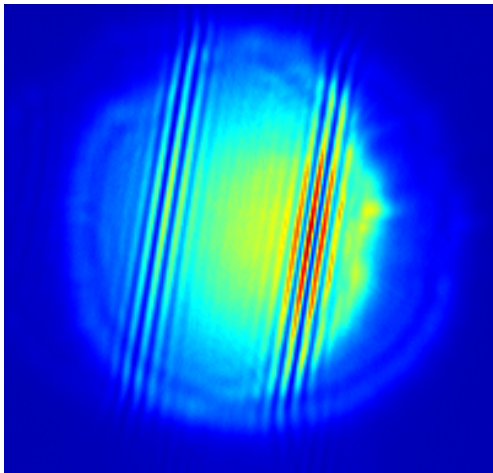
- HHG in Argon with  $>1$  mJ  $\sim 20$  fs pulses
- Individual pulses should not influence each other during the HHG process  $\rightarrow$  spatially separated HHG zones.
- Collinear beams, overlap after finite distance due to beam divergence.



# HHG Fourier transform spectroscopy

- Fourier transformation of the time delay scan on a single pixel yields the spectrum at the location of that pixel.
- Linear autocorrelation of two HHG beams yields coherence length.

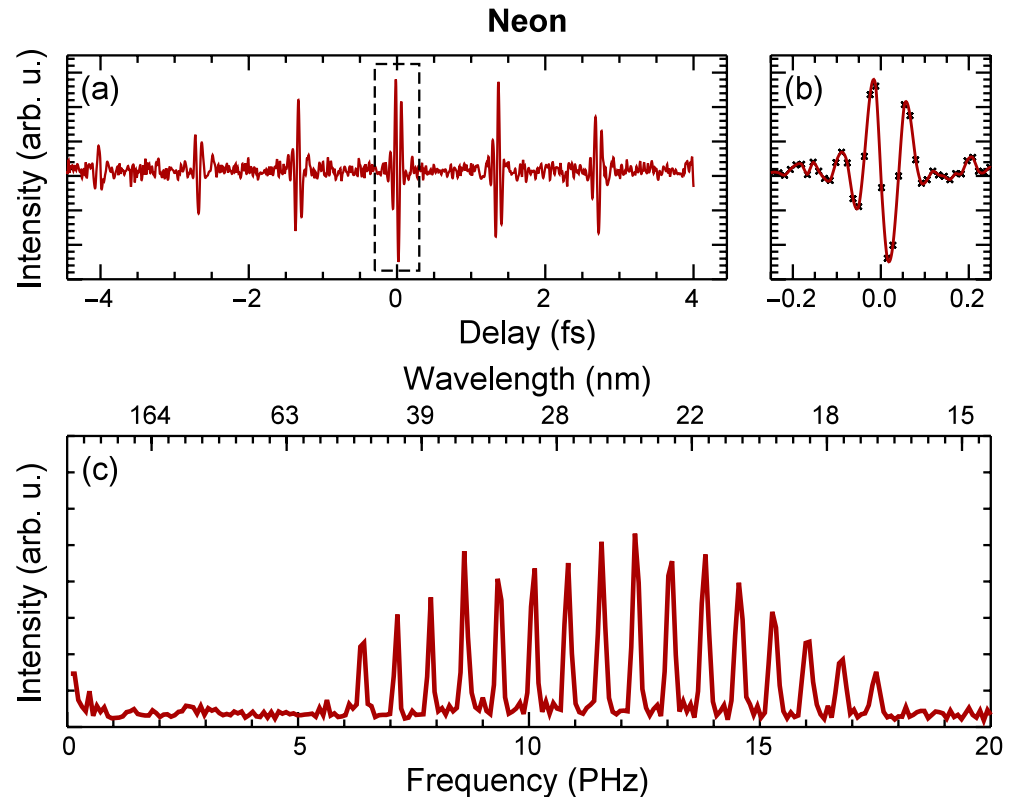
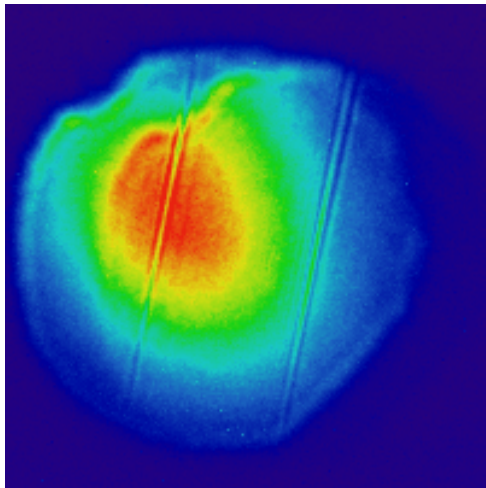
HHG-FTS in Argon:



# HHG Fourier transform spectroscopy

- HHG in Neon yields broader spectra and shorter coherence times.
- HHG detected down to 17 nm wavelength (Al filter cutoff).
- Stability of interferometer and HHG phase coherence maintained at sub-nm level.

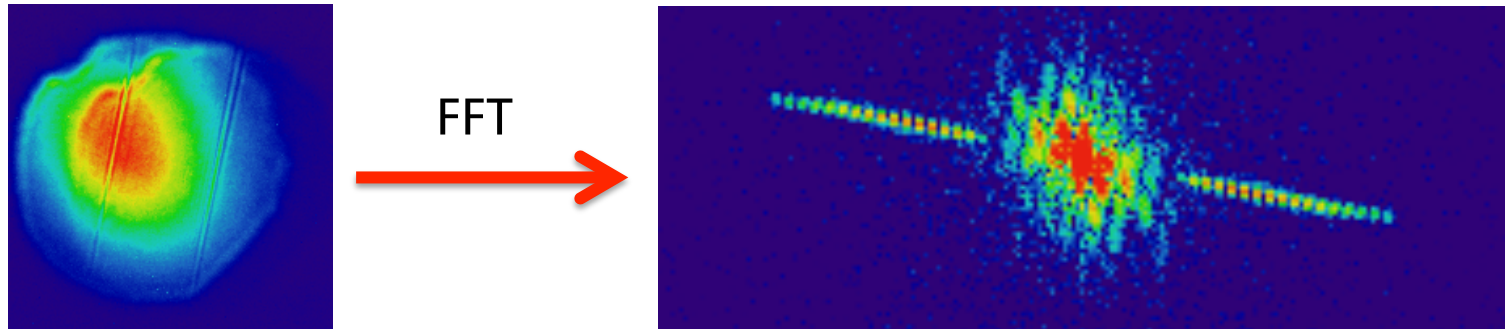
HHG-FTS in Neon:



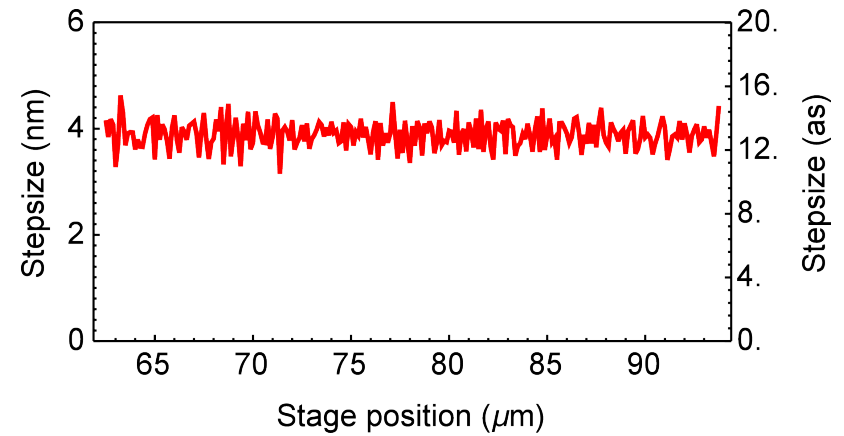
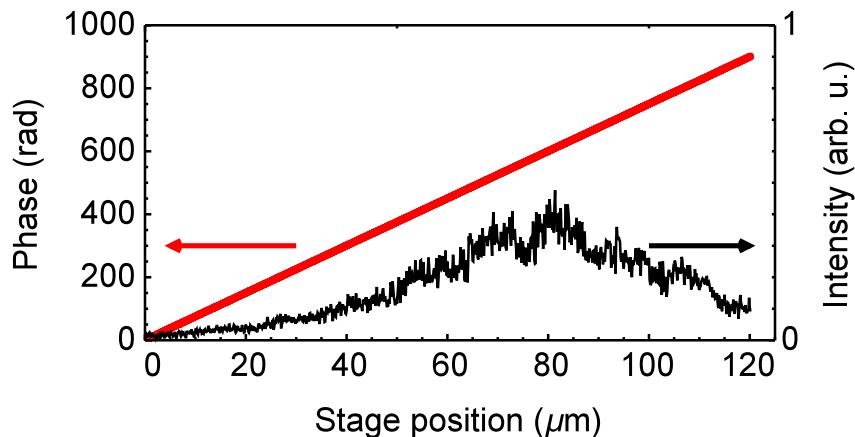


# Spatial interference and interferometer stability

Spatial Fourier transform yields a single-shot HHG spectrum:



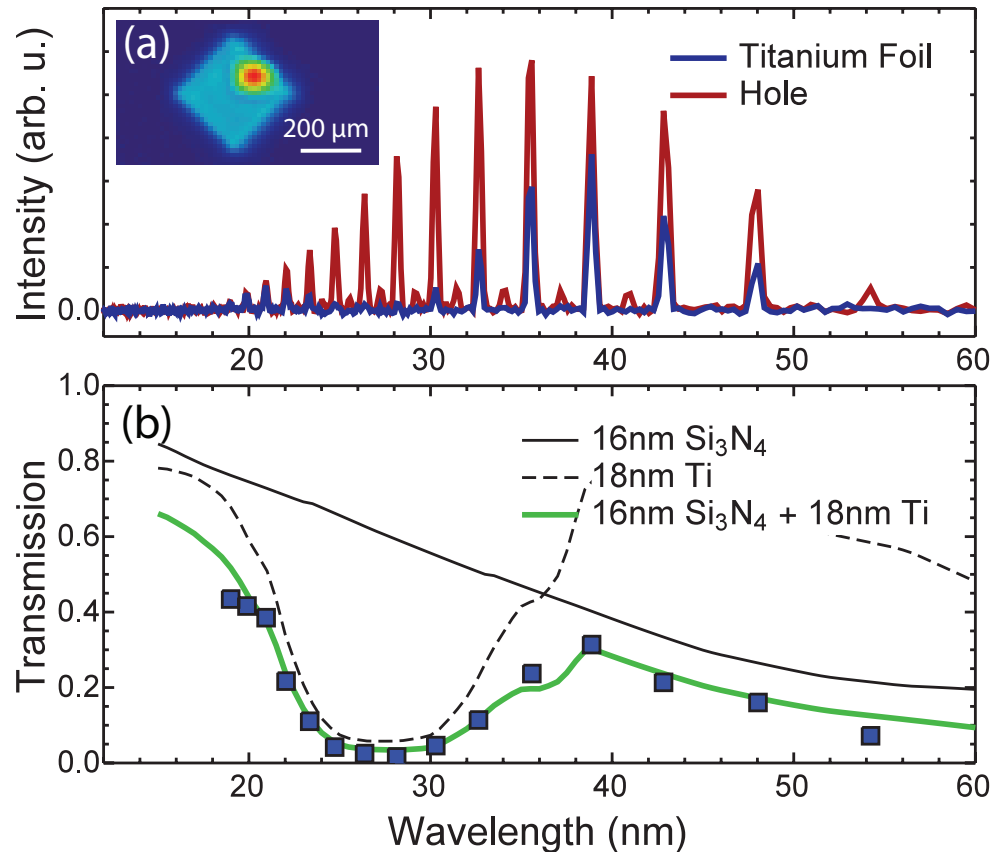
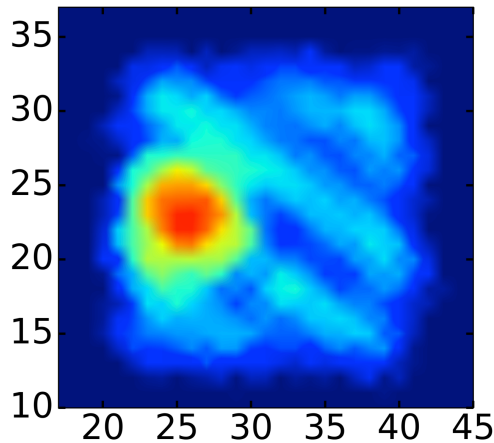
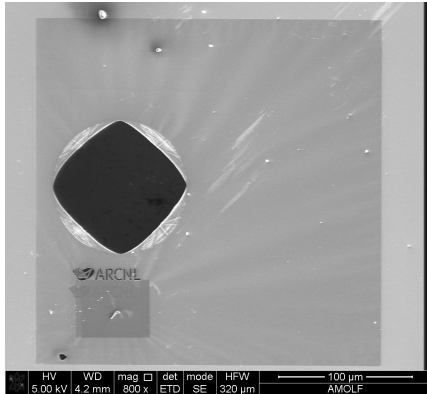
Phase detection of a single harmonic vs time delay yields timing stability:



Measured RMS timing stability of 0.8 as, or 0.25 nm optical path length

# Spatially resolved XUV spectroscopy

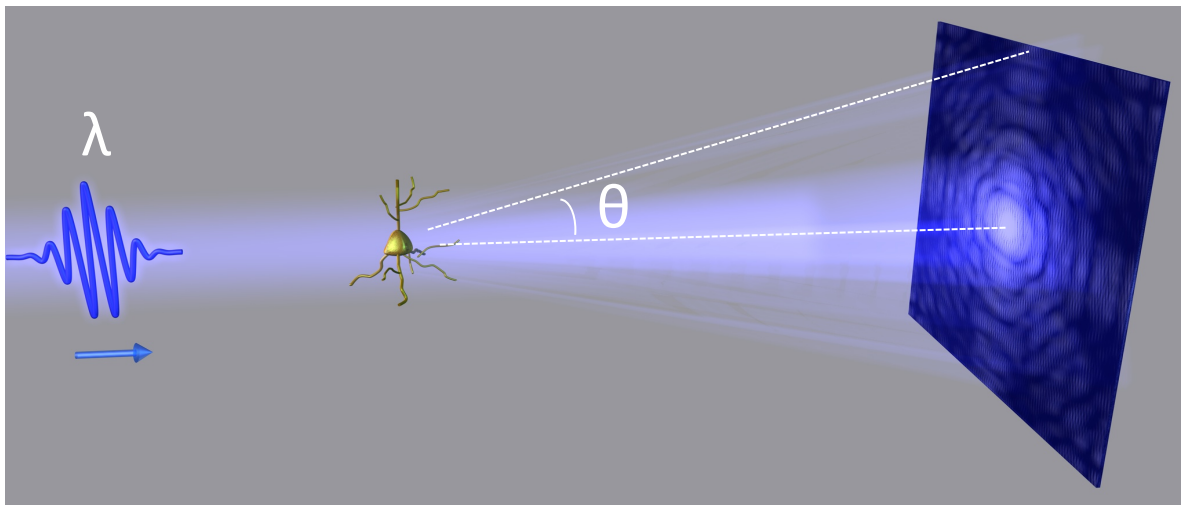
Titanium layer on 250x250  $\mu\text{m}$  silicon nitride foil with a 50  $\mu\text{m}$  hole in it:



Measurement of the transmitted spectrum of Neon HHG on each CCD pixel

# Lensless coherent diffractive imaging

Numerical reconstruction of an object from a coherent diffraction pattern, instead of the use of optical components for image formation:

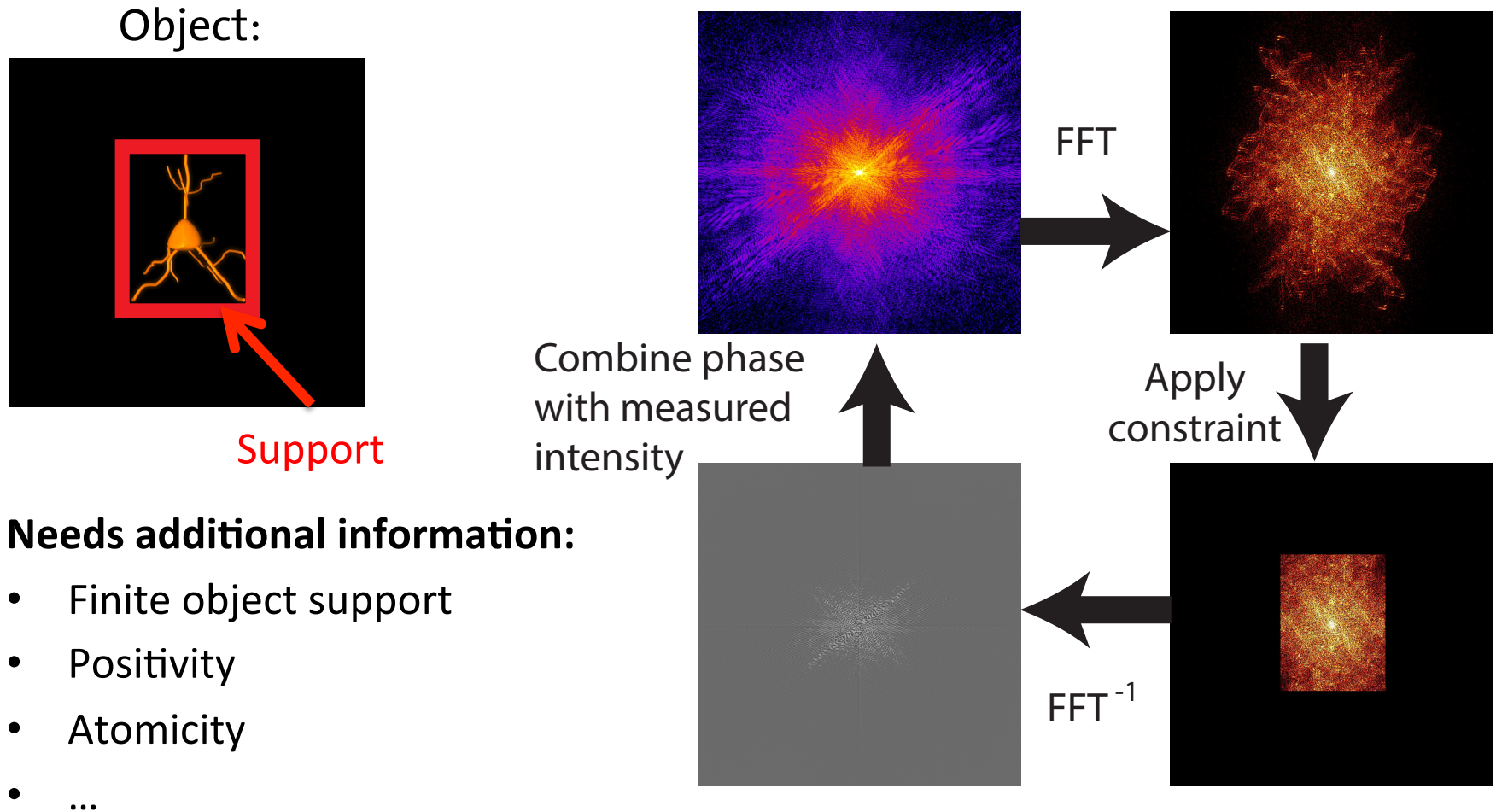


Measured diffraction yields intensity, phase also needed for image reconstruction

→ The challenge is to retrieve the missing phase information.

- Resolution =  $\lambda / 2 \sin \theta$
- High spatial and temporal coherence important.

# Image reconstruction from a diffraction pattern



Other approaches use multiple measurements instead of an object constraint (ptychography, multi-wavelength/multi-distance phase retrieval, etc.)

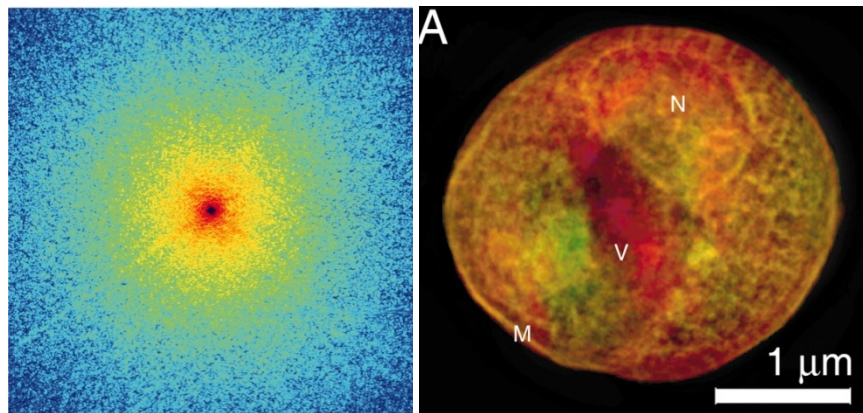
J.R. Fienup, Appl. Opt. **21**, 2758, (1982)

J. Miao et al., Nature **400**, 342 (1999)

# Coherent diffractive imaging: examples

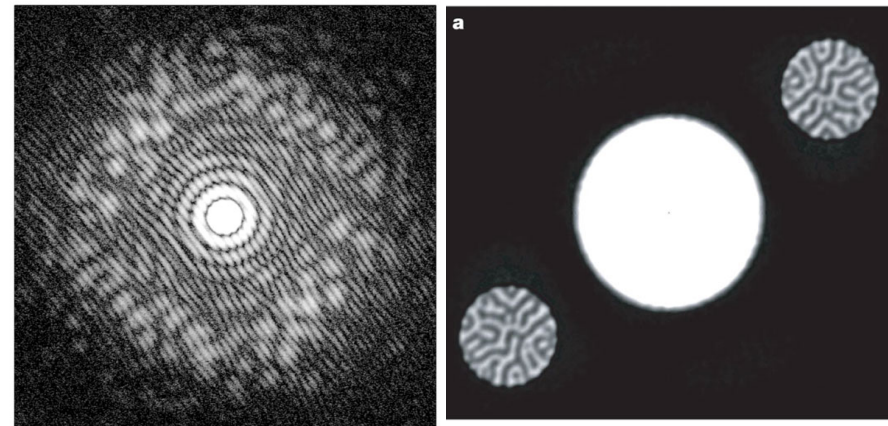
- Several successful experiments have been performed using CDI.
- Resolutions of 20-25 nm achieved.

Freeze-dried yeast cell at 30 nm resolution  
Synchrotron, 750 eV photons:



D. Shapiro et al., PNAS **102**, 15343 (2005)

Magnetic nanostructures, 50 nm resolution  
Synchrotron, 778 eV photons:



S. Eisebitt et al., Nature **432**, 885 (2004)

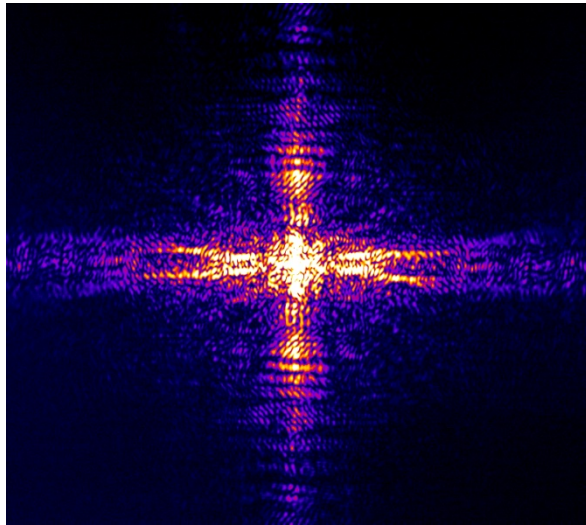


# Bandwidth limitations in lensless imaging

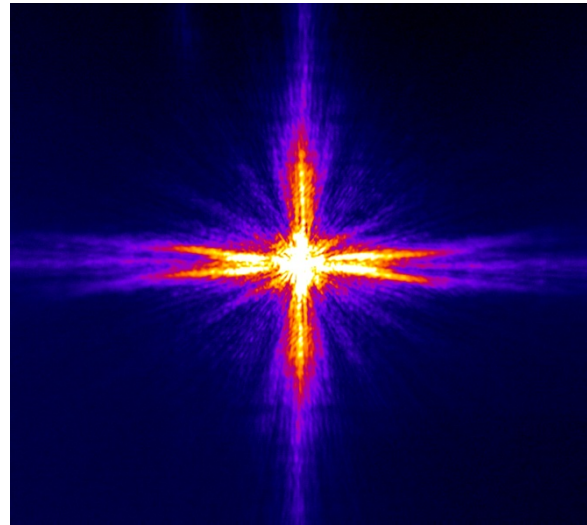
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- Lensless imaging requires a coherent, monochromatic source, since the diffraction angle is directly proportional to wavelength.
- Broadband sources lead to blurred diffraction patterns:

Monochromatic:



Broadband:



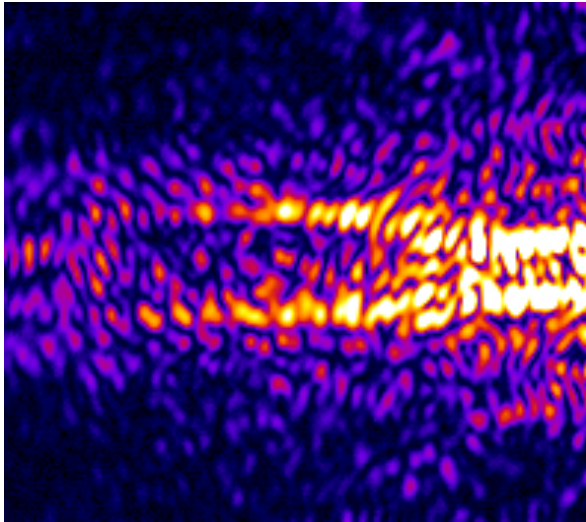
- Limits the resolution, in extreme cases prevents image reconstruction.
- Spectral filtering is possible, but at the cost of serious flux reduction.

# Bandwidth limitations in lensless imaging

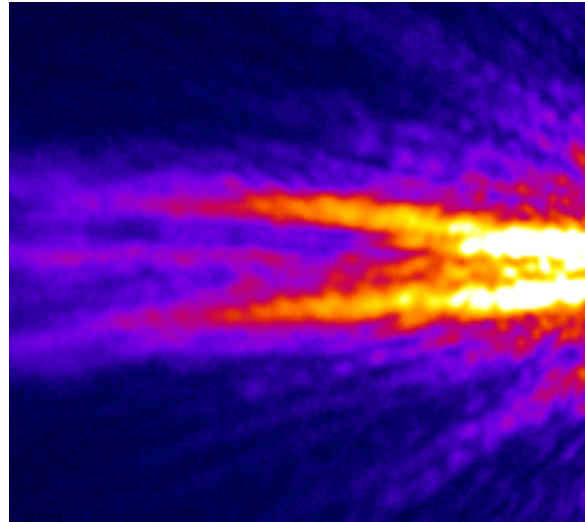
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- Lensless imaging requires a coherent, monochromatic source, since the diffraction angle is directly proportional to wavelength.
- Broadband sources lead to blurred diffraction patterns:

Monochromatic:



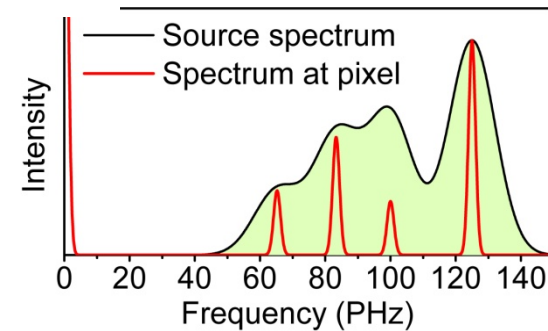
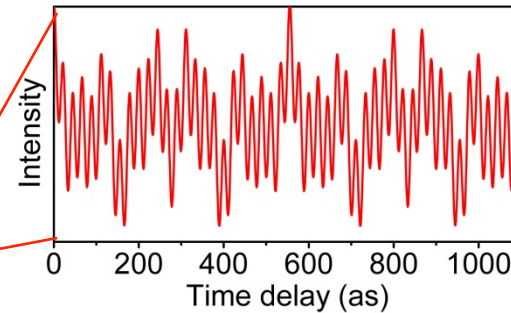
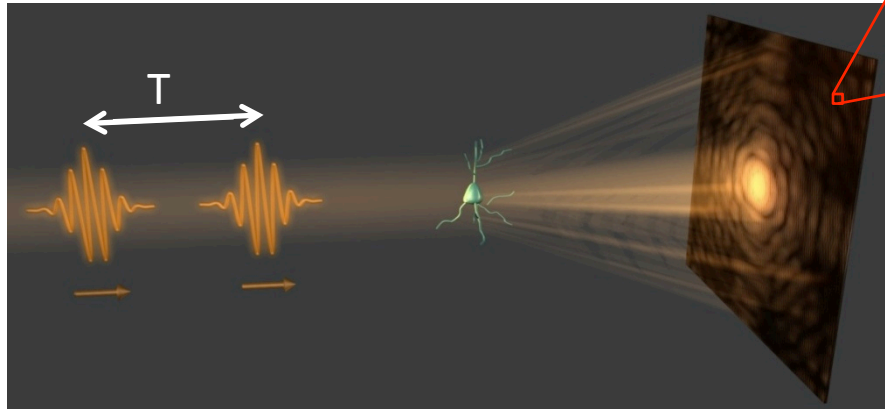
Broadband:



- Limits the resolution, in extreme cases prevents image reconstruction.
- Spectral filtering is possible, but at the cost of serious flux reduction.

# Two-pulse Fourier-transform imaging

- Combination of imaging and Fourier transform spectroscopy
- On each CCD pixel, a Fourier-transform spectrum is recorded of the light diffracted onto that specific pixel.

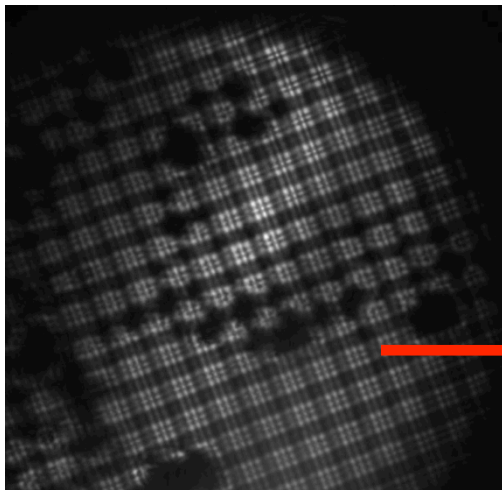


- Allows reconstruction of 'monochromatic' diffraction patterns for all spectral components in the pulse.
- The full spectrum is used throughout the entire measurement.

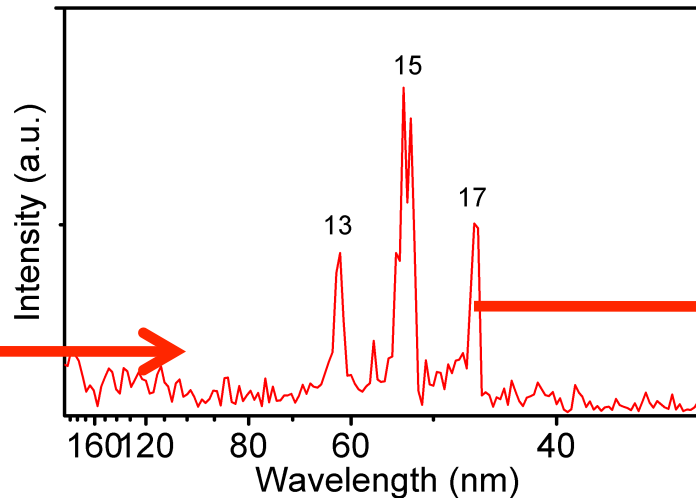
# Lensless imaging with XUV radiation

- Sample is a Nickel grid on a 300 nm thick Aluminium foil.
- The Al-foil is partially transparent below 70 nm wavelength.
- Spectrally resolved images at 62, 53 and 47 nm wavelength.
- Scan parameters: 512 steps of 6.6 nm (22 attoseconds).

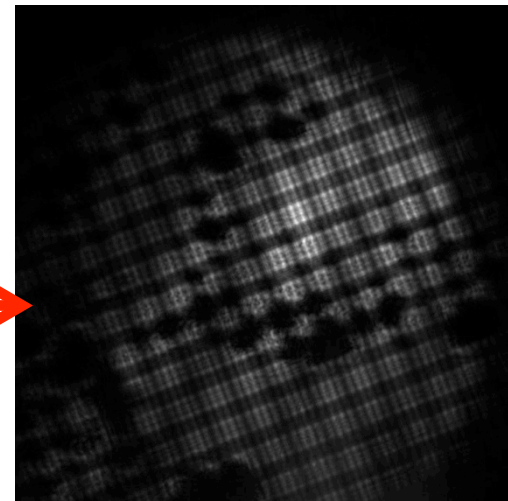
Broadband diffraction:



HHG spectrum:



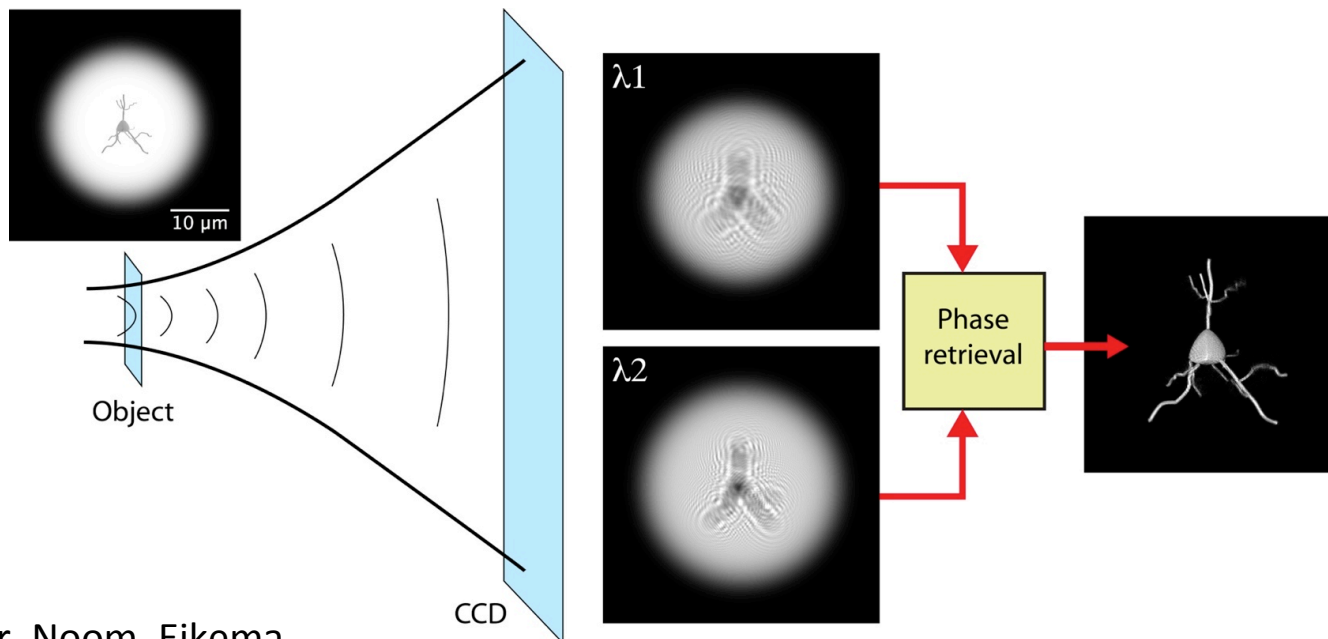
Diffraction at  
17<sup>th</sup> harmonic:



# Multi-wavelength iterative phase retrieval

- For Fresnel diffraction, measurements at multiple propagation conditions enable unique image reconstruction.
- The Fresnel diffraction integral describes the field propagation:

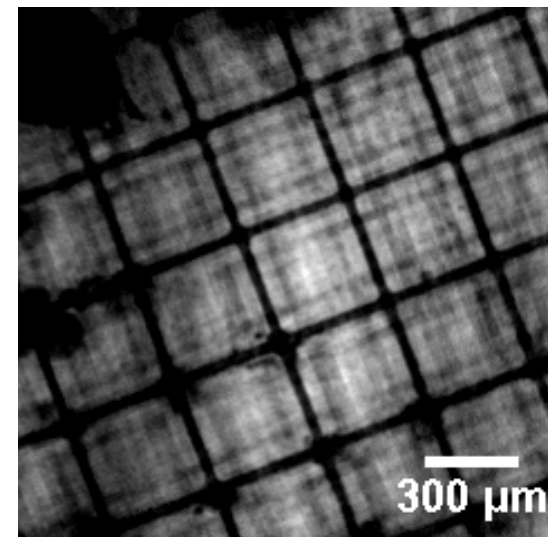
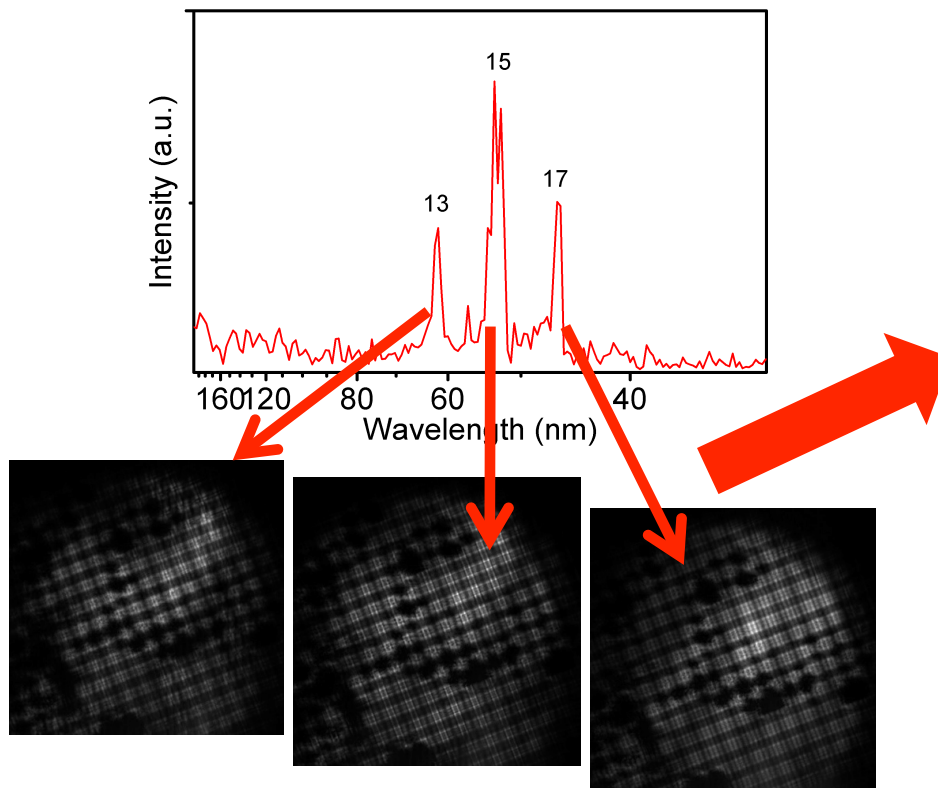
$$E(x, y, z) = \frac{e^{ikz}}{i\lambda z} \iint E(x', y', 0) e^{\frac{i\pi}{\lambda z} [(x-x')^2 + (y-y')^2]} dx' dy'$$





# Lensless imaging at short wavelengths

- We use diffraction patterns at 62 nm, 53 nm and 47 nm as input for our multi-wavelength phase retrieval algorithm.
- Resolution limited by NA to  $6.8\text{ }\mu\text{m}$ , can easily be improved in future experiments.



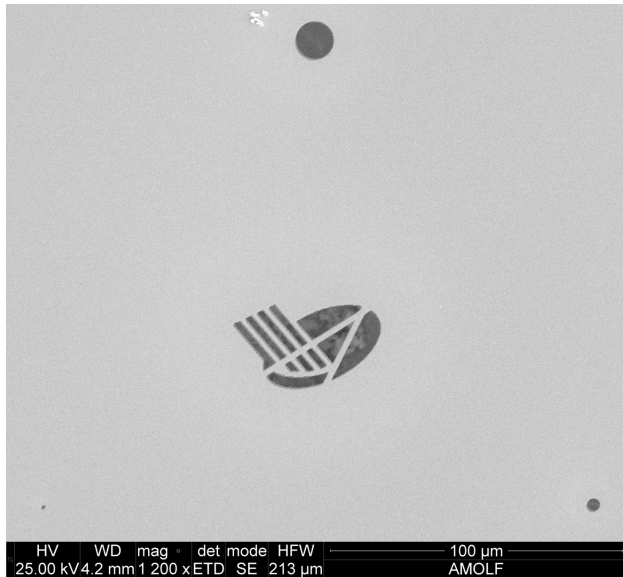
Nickel grid behind  
200 nm thick Aluminium layer

Witte, Tenner, Noom, Eikema,  
Light: Sci. Appl. **3**, e163 (2014)

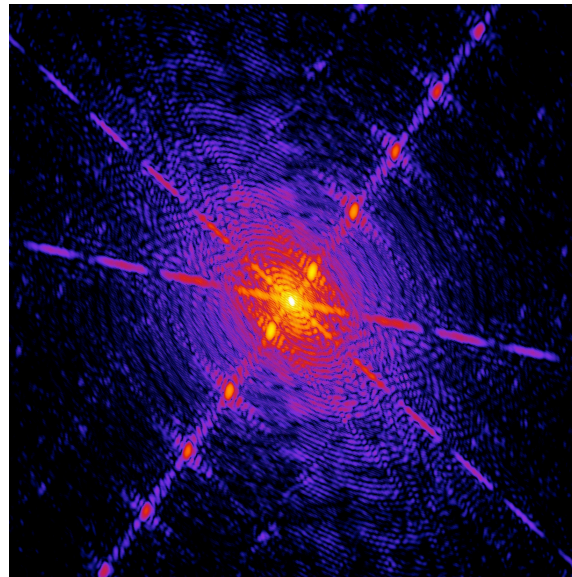
# XUV Fourier-transform holography

- Fourier-transform holography provides a direct phase measurement.
- Pinhole-generated reference wave acts as a delta function.
- Signal intensity:  $I = |E_{ref}|^2 + |E_{obj}|^2 + E_{ref}E_{obj}^* + E_{ref}^*E_{obj}$

Sample



Hologram:  $|FT|^2$



Reconstruction:  $FT^{-1}$

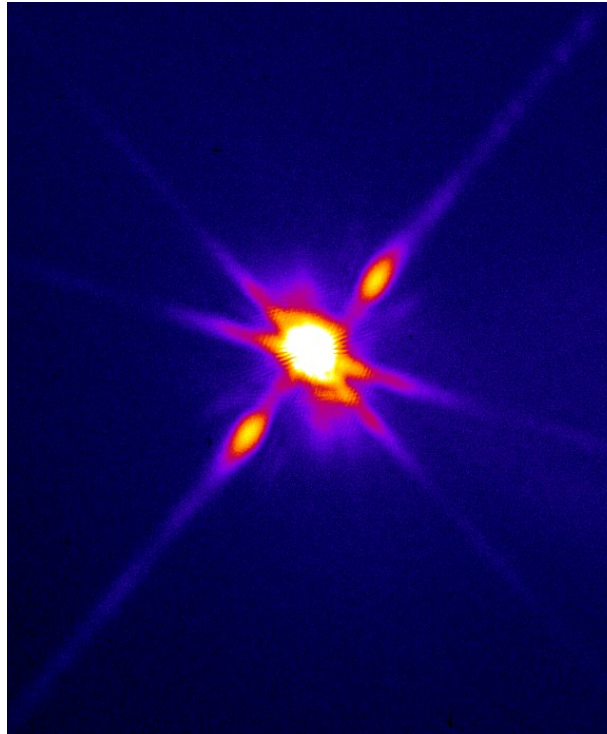


- Resolution limited by aperture diameter
- Signal proportional to aperture area ( $\sim d^2$ )

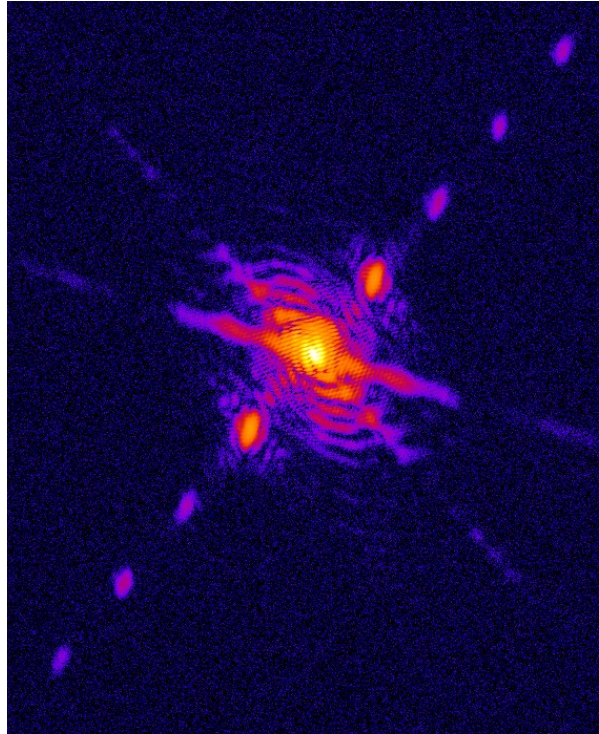
# XUV holography

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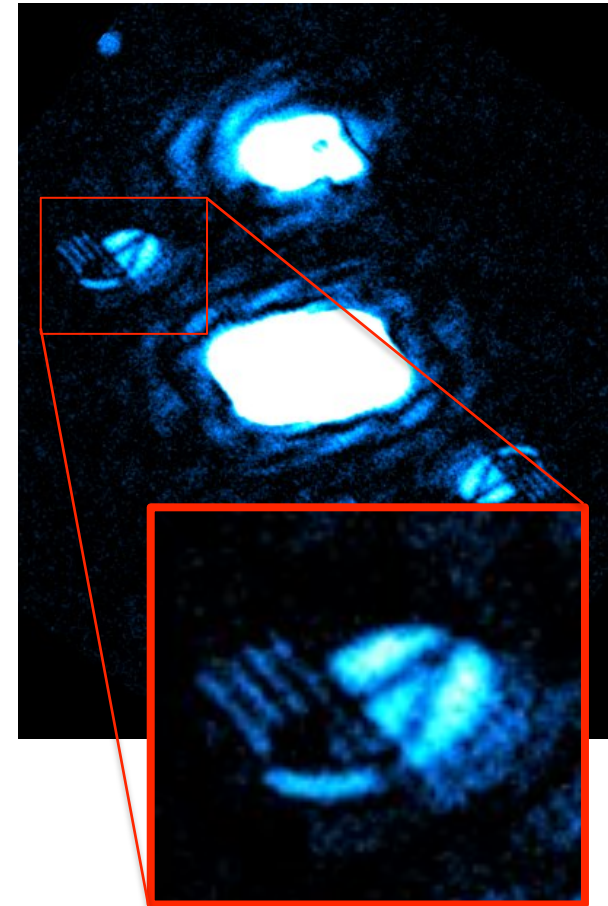
Broadband hologram:



Hologram at  $\lambda=33$  nm:



Fourier transform:



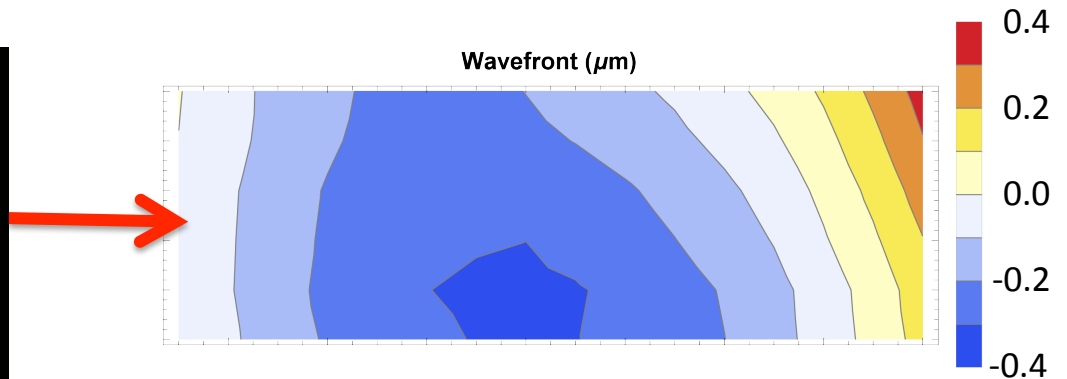
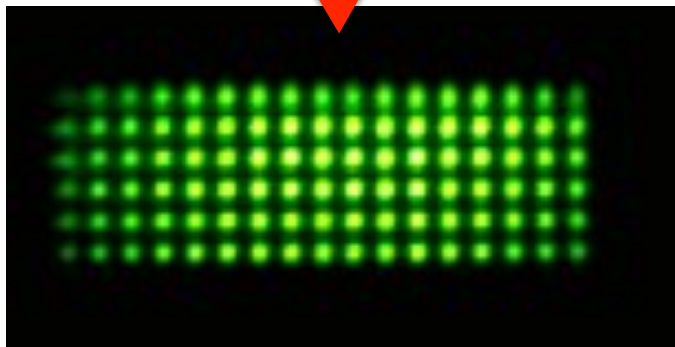
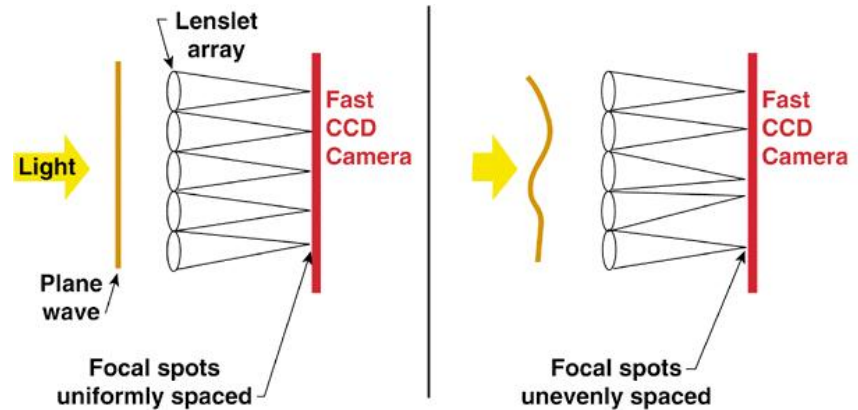
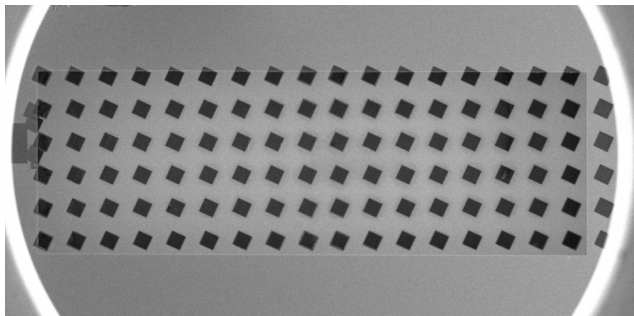
- Signal from smallest pinhole below noise level
- Flux limited by HHG beam size
- Next step: focus the XUV beam



# HHG wavefront measurements

Alternatively, known structures can be used to diagnose the XUV beam itself

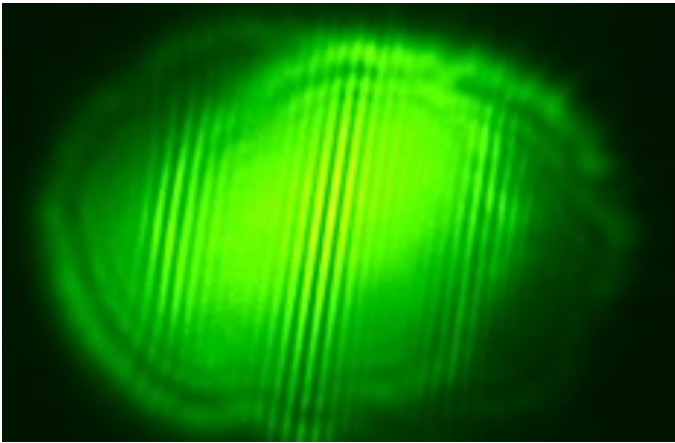
Hartmann mask:



2D wavefront reconstruction, can be combined with two-pulse scan for spectral resolution

# HHG wavefront measurements

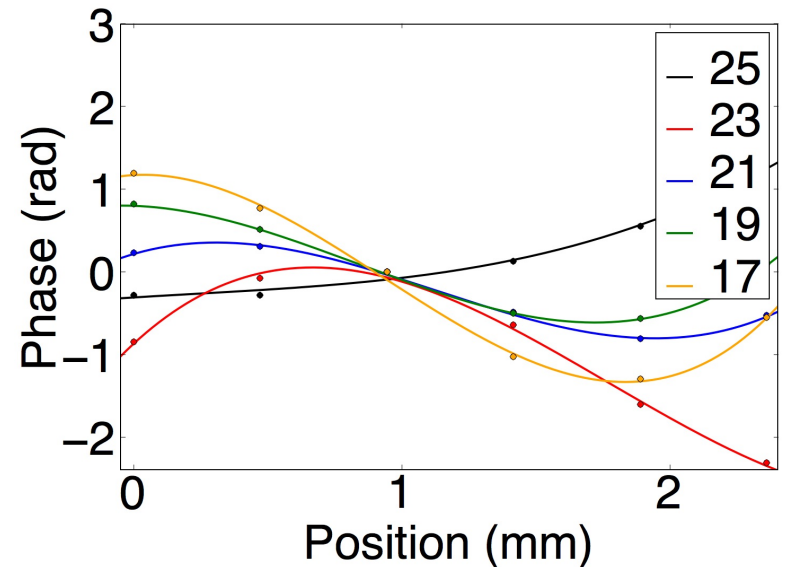
Lateral shearing interferometry: interference of two displaced copies of a HHG beam.



Provides a spatial derivative of the phase:

$$\psi(x) = \varphi(x + \Omega) - \varphi(x)$$

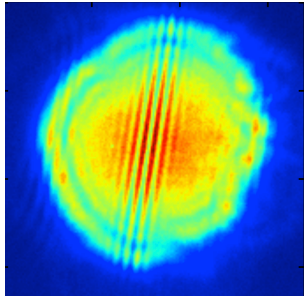
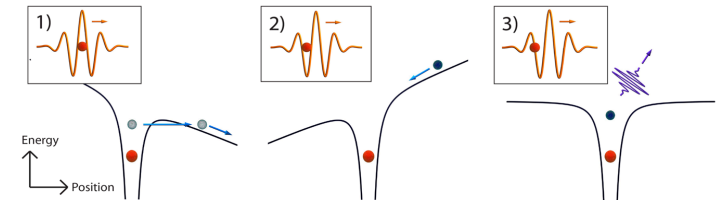
With a known 'shear'  $\Omega$ , integration yields the spatial phase  $\varphi(x)$



Single-shot spectrally resolved measurement (but 1D information)

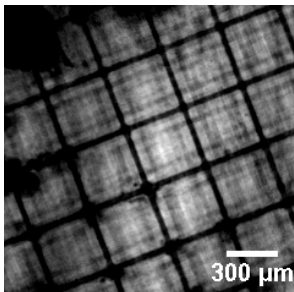
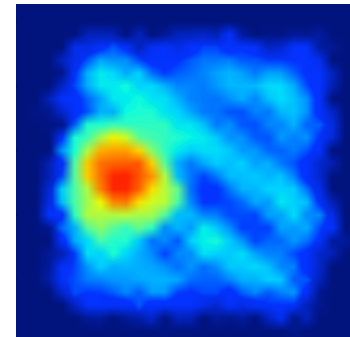
# Conclusions

High harmonic generation is a versatile tool for extreme ultraviolet experiments with a table-top setup, such as:



- Interferometry with HHG beams at 17 nm wavelength and beyond.

- Fourier transform spectroscopy with HHG, enabling spatially resolved XUV spectroscopy.



- Spectrally resolved lensless XUV imaging, using the full spectrum and flux of a HHG source.



# EUV Generation and Imaging @ ARCNL

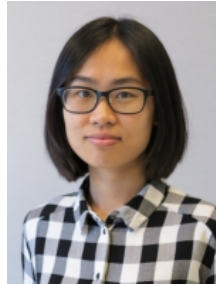
## PhD students



Tiago  
Pinto



Lars  
Freisem



Mengqi  
Du



Alessandro  
Antoncecchi



Randy  
Meijer



Dirk  
Boonzajer  
Flaes



Matthijs  
Jansen

## Group leaders



Stefan  
Witte



Kjeld  
Eikema

## Postdocs



Aneta  
Stodolna

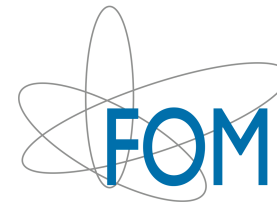


Denis  
Rudolf

## Technician



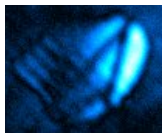
Nik  
Noest



European Research Council  
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## Jobs and internships

### ► Group leader / assistant professor: High-harmonic generation and EUV physics

October 25, 2016 · [Group leaders](#)

The Advanced Research Center for Nanolithography (ARCNL) is looking for a tenure-track group leader in the field of EUV physics and high-harmonic generation. The successful candidate will develop a world-class ...

### ► Lensless microscopy and 3D imaging with visible and EUV sources

September 26, 2016 · [Postdoc positions](#)

The postdoc will develop new methods for high-resolution lensless microscopy using visible, near-infrared and extreme ultraviolet radiation. You will work on high-speed imaging applications, visualization of (sub-)surface features in metals ...

### ► Master student projects in Nanophotochemistry ARCNL

April 13, 2016 · [Scientific internships](#)

The overall goal of our research is to understand the fundamental physical and chemical factors that determine the efficiency and quality of pattern formation in Extreme Ultraviolet nanolithography/Various student projects

### ► Ionic interactions in EUV-generating plasmas

March 8, 2016 · [PhD positions](#)

The group EUV plasma dynamics at ARCNL is looking for a PhD-student to work on 'Ionic interactions in EUV-generating plasmas'. The PhD project aims at unveiling and quantifying the fundamental ...